What is claimed is:

1.    A defect source identifier that provides information used to identify a source of a defect on a substrate, which defect source identifier comprises:

a LotRoute database generation process and a LotRoute database access process, wherein:

the LotRoute database generation process comprises a software application that runs on a server and that, in response to user input, defines a wafer route including wafer route information, and associates the wafer route with any one of a number of entities; and

the LotRoute database process comprises a software application that runs on the server and that, in response to input from the defect source identifier, retrieves the wafer route information using an identifier of one of the entities.

2.    The defect source identifier of claim 2 wherein the entities are one of Lot ID, Step or Layer ID, Inspection/Review Tool ID, and Fixed Route ID.

3.    The defect source identifier of claim 2 wherein the LotRoute database generation process designates the wafer route associated with the Route ID as a default route.

4.    The defect source identifier of claim 3 wherein the wafer route information associated with an entity comprises one or more tools specified by one or more tool type and tool identifier.

5.    The defect source identifier of claim 4 wherein the LotRoute database generation process enables a user to add, edit, or delete a wafer route.

6.    The defect source identifier of claim 5 wherein the LotRoute database process comprises a retrieval algorithm that retrieves wafer route information by searching for a wafer route using Lot ID as a retrieval key, and if a wafer route associated with the Lot ID is found, returning the wafer route information; otherwise by searching for the wafer route using Step ID as a retrieval key, if specified, and if a wafer route associated with the Step ID is found, returning the wafer route information, otherwise by searching for the wafer route using Tool ID as a retrieval key, if specified, and if a wafer route associated with the Tool ID is found, returning the wafer route information, otherwise by returning the default wafer route information.